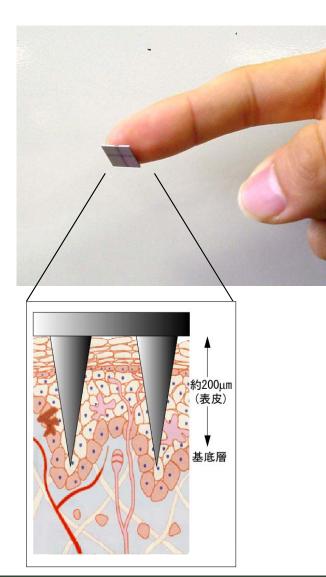
Advanced 6 Advanced MEMS applications -Micro-needle for trans-dermal DDS--Portable biochemical reaction system-

Associate Prof. M. Shikida Center for Micro-nano Mechatronics Nagoya University





Micro-needle for trans-dermal DDS



Requirements of needle development
✓Sharpness of needle tip
✓Sufficient height for skin penetration
✓High density for drug supply
✓Disposable, low-cost





Advanced MEMS fabrication

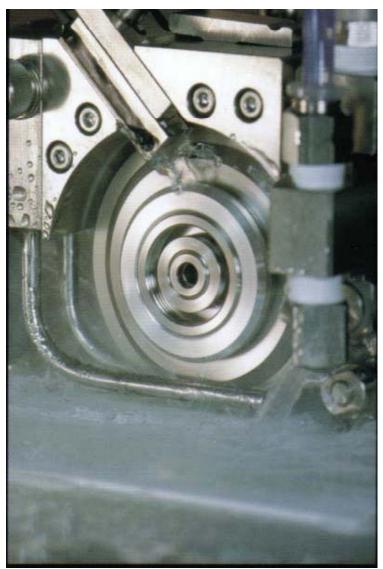
Fabrication step
① 2.5D shape formation by grinding
② 3D shape production by anisotropic wet etching

 Advantages
 ✓ Low facility investment
 It can produce MEMS device without using photolithography and Deep reactive ion etching.
 ✓ Production of high aspect ratio micro-structure





Advanced MEMS fabrication _ Grinding process







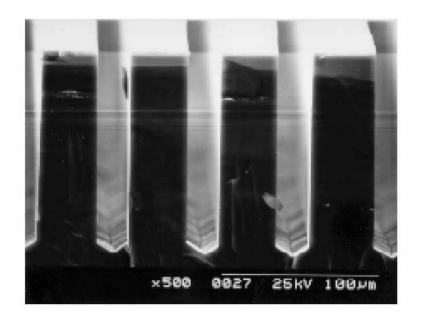


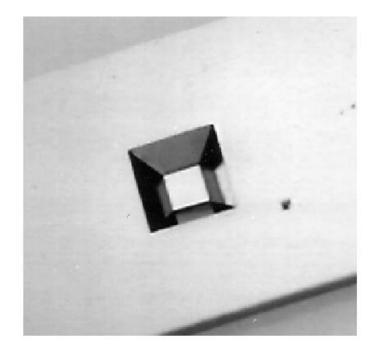
Blade Thickness: 0.025 mm, 0.050 mm Particle size: #2000

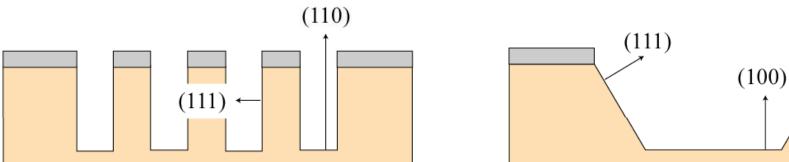




Advanced MEMS fabrication _ Anisotropic wet etching







Etching rate depends on crystallographic orientation.



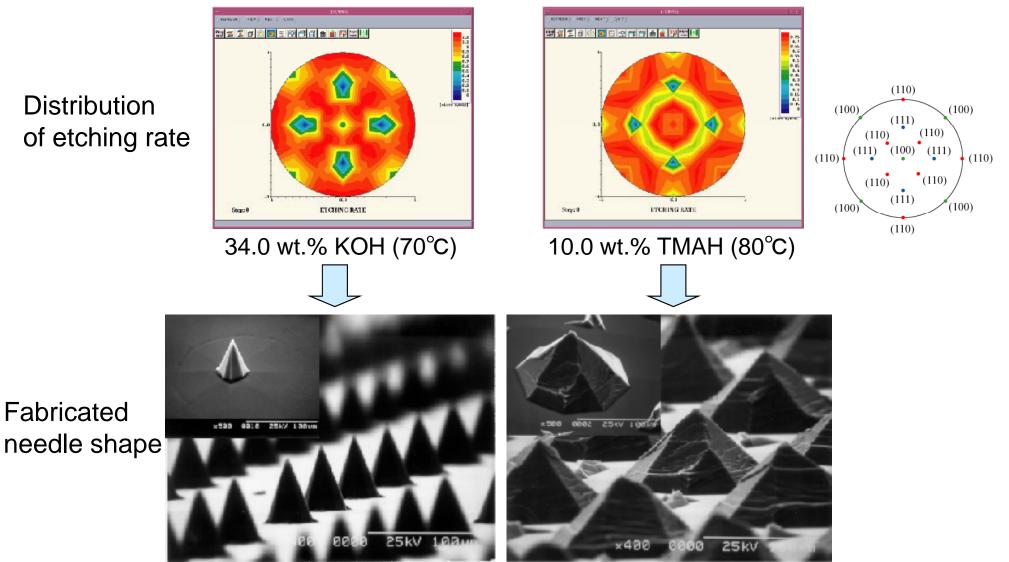
Advanced 6 Advanced MEMS applicationsAssociate Prof. M. ShikidaCOE for Education and Research of Micro-Nano Mechatronics, Nagoya University



SiO₂

Si

Dependency of etching rate distribution

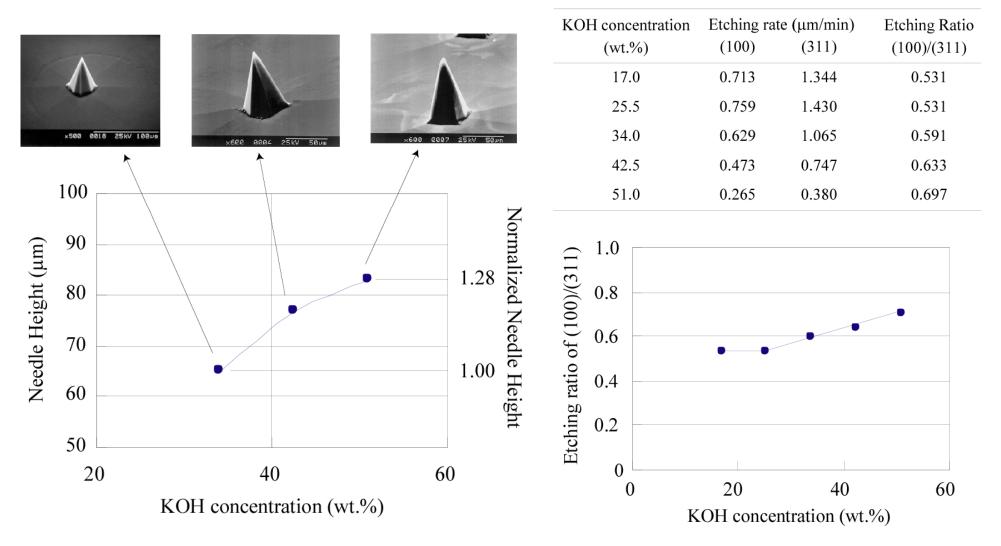


H. Sasaki, et al., IEEJ Trans Electrical Electronic Eng., 2, 2007, 340-347





Dependency of concentration

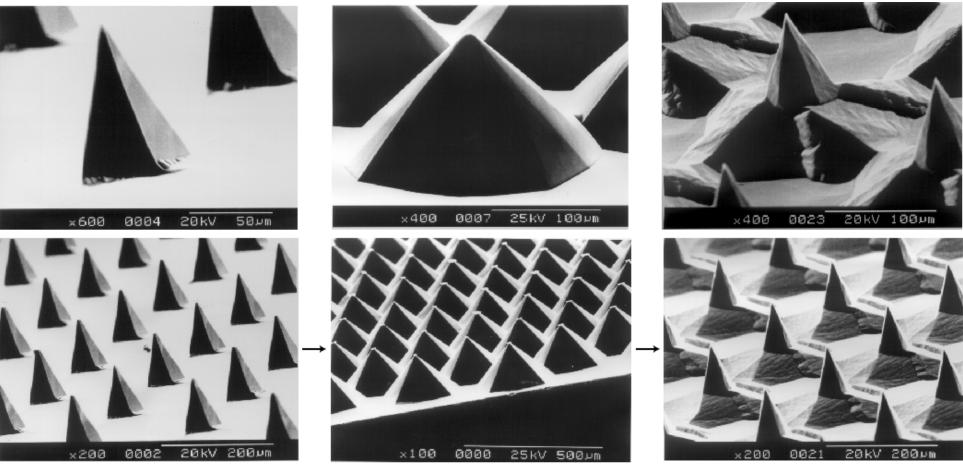


H. Sasaki, et al., IEEJ Trans Electrical Electronic Eng., 2, 2007, 340-347





Shape change with change of etching solution



51.0 wt.% KOH (71 deg-C)

25.0 wt.% TMAH with surfactant (75 deg-C)

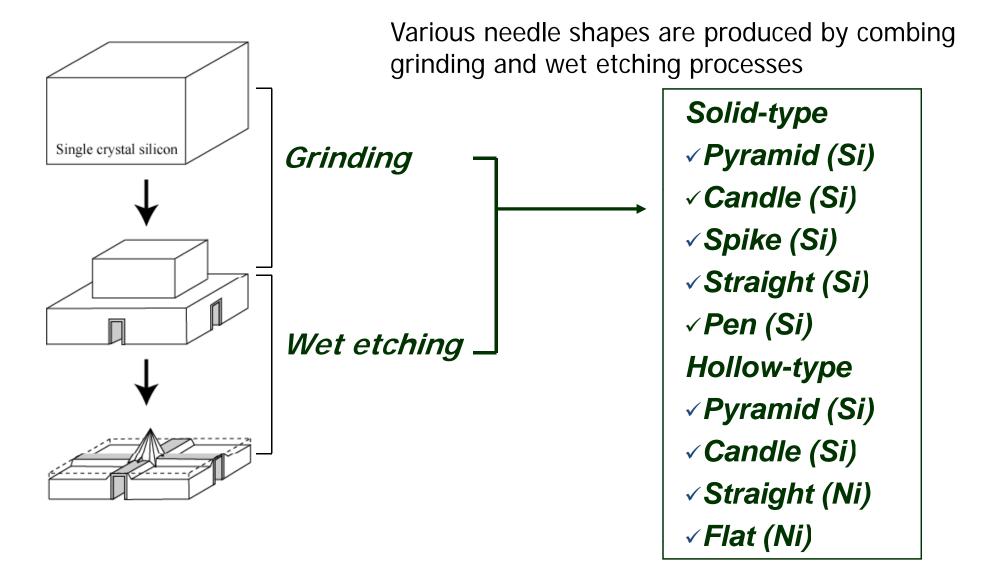
Windmill shaped mask pattern



51.0 wt.% KOH (69 deg-C)



Advanced MEMS fabrication

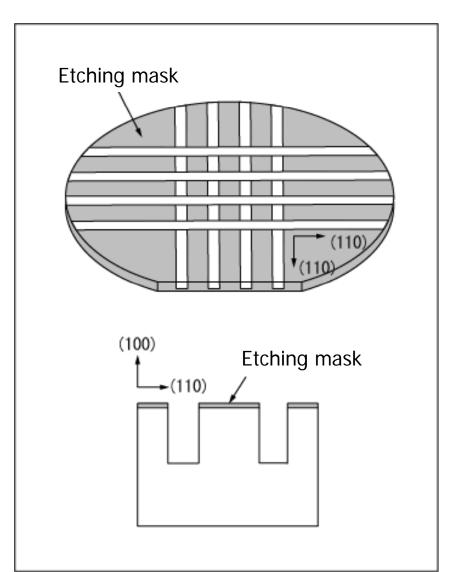






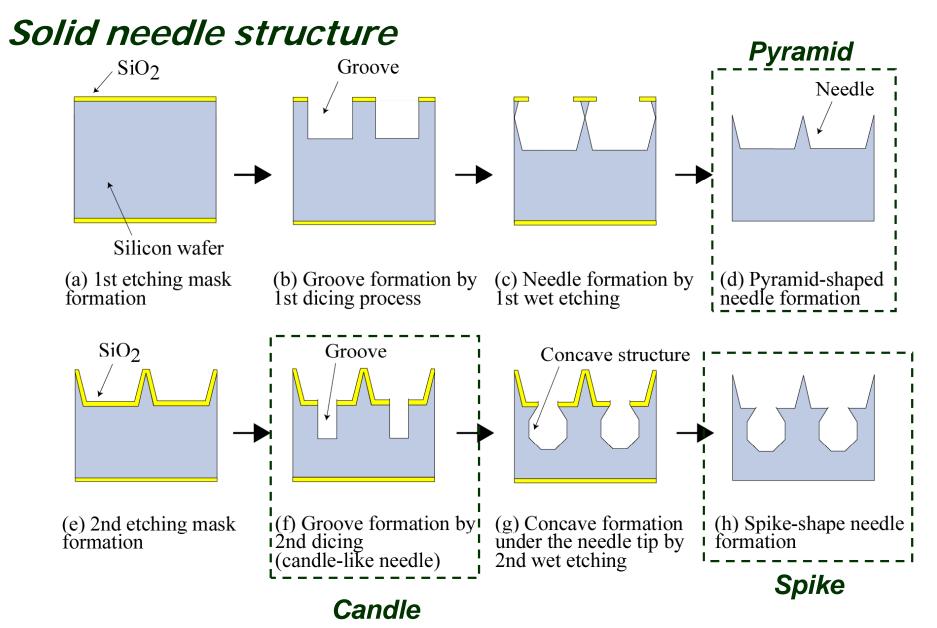
Advanced MEMS fabrication _ Recipe

- ✓ Si(100) wafer
- ✓ Blade
 - ✓ #2000 (4/6 micron)
 - ✓ Thickness: 0.025, 0.050 mm
- ✓ Grinding
 - ✓ Direction <110>
 - $\checkmark\,$ Groove depth : 40 400 μm
 - $\checkmark\,$ Groove width : 30 180 μm
 - ✓ Pitch : 70 200 µm
 - ✓ Cutting speed: 5 mm/s
- ✓ Etching: KOH40%, 70°C







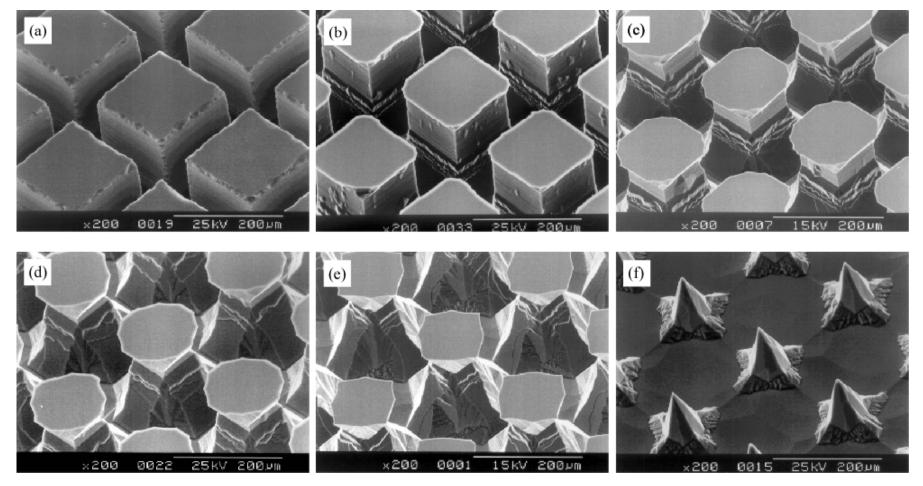


M. Shikida, et al., Sensors and Actuators A, 116, 2004, 264-271





Solid needle structure _ shape change during etching



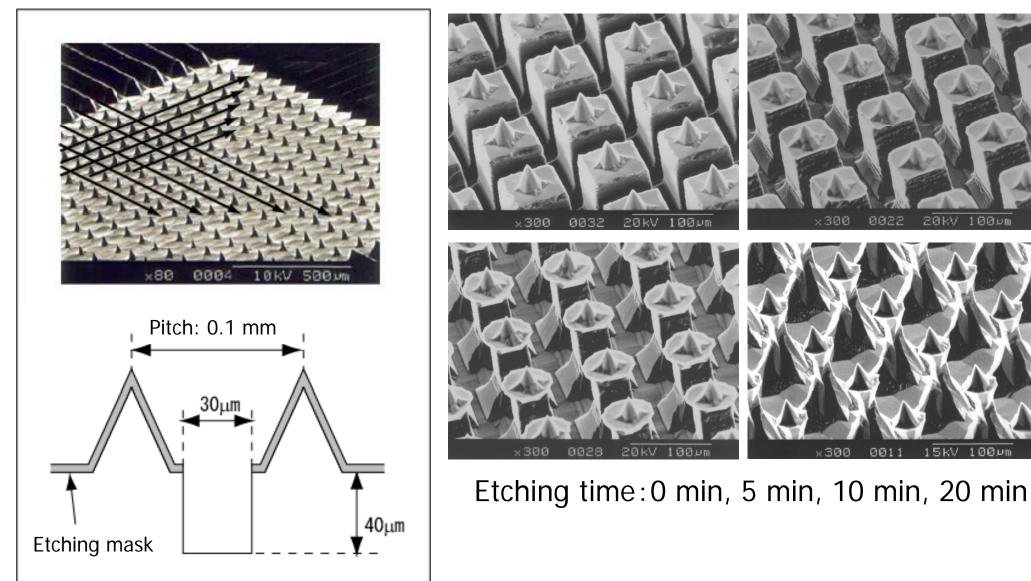
Etching time: (a) 0 min, (b) 15 min, (c) 30 min, (d) 40 min, (e) 50 min, (f) 105 min

M. Shikida, et al., Sensors and Actuators A, 116, 2004, 264-271





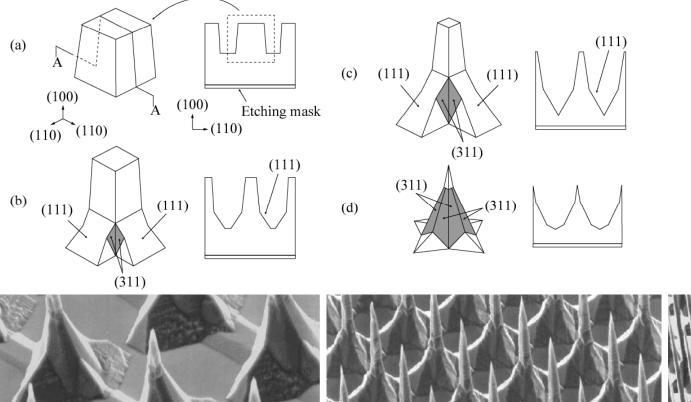
Solid needle structure _ shape change during 2nd etching

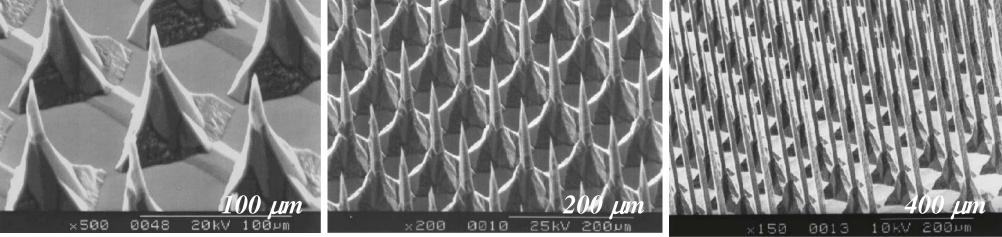






Solid needle structure _ straight



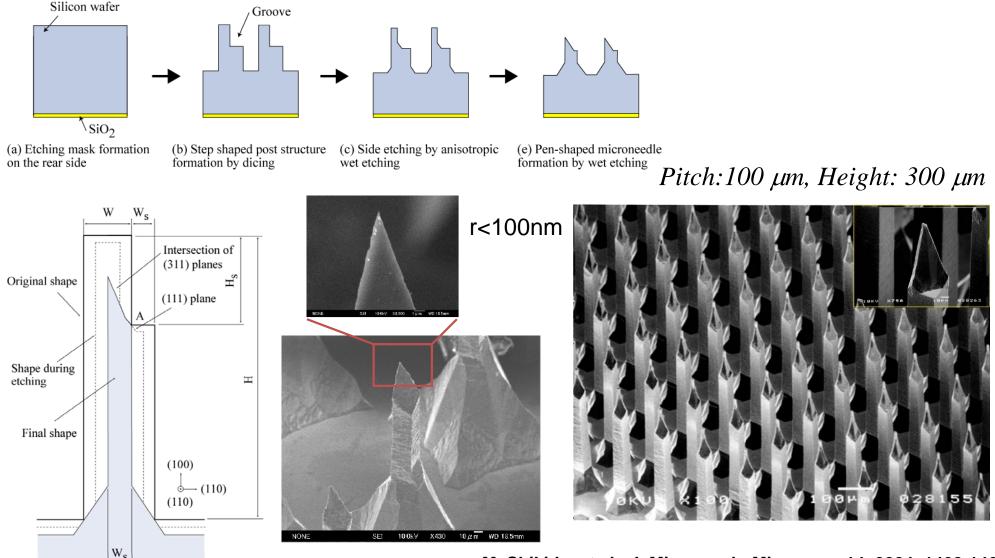


M. Shikida, et al., Sensors and Actuators A, 116, 2004, 264-271





Solid needle structure _ Pen-shape

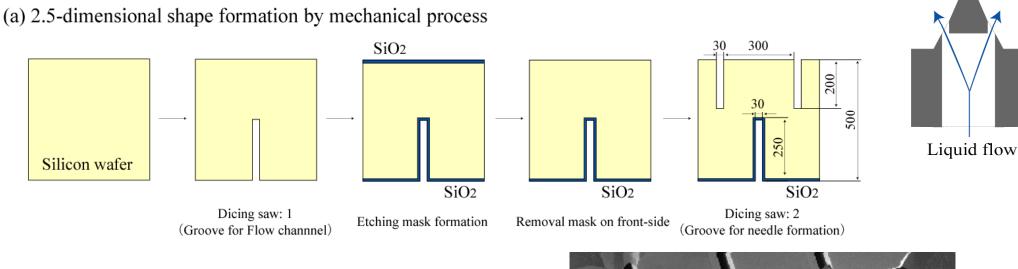


M. Shikida, et al., J. Micromech. Microeng., 14, 2004, 1462-1467

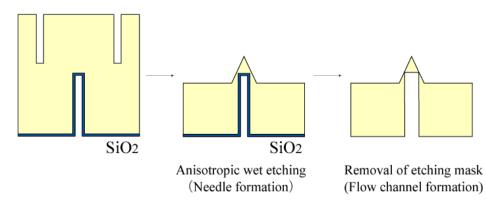


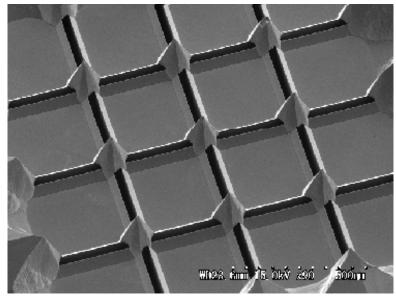


Hollow needle structure



(b) Needle formation by anisotropic wet etching



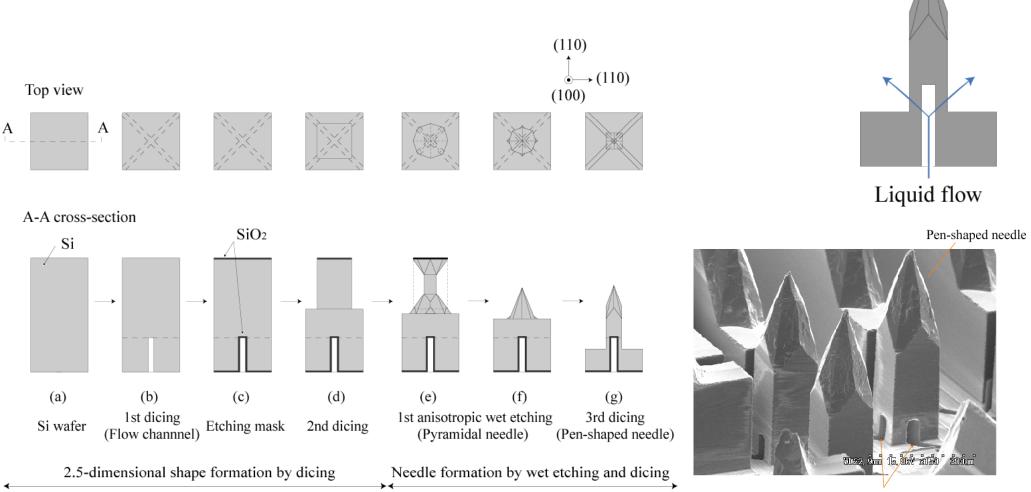


M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 1740-1747





Hollow needle structure



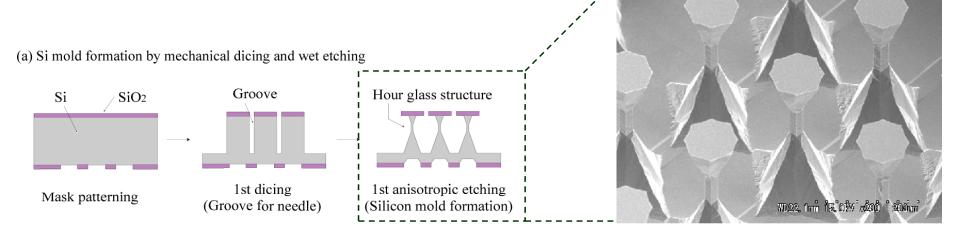
Opening mouth of flow channel

M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 1740-1747

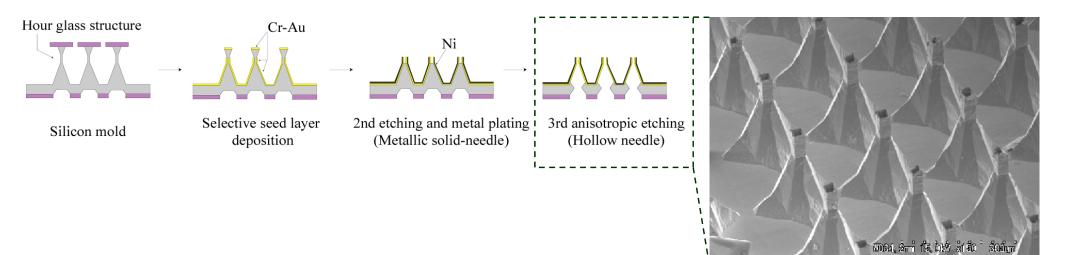




Hollow needle structure



(b) Pyramidal-shaped hollow needle formation by metal deposition and etching



M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 2230-2239





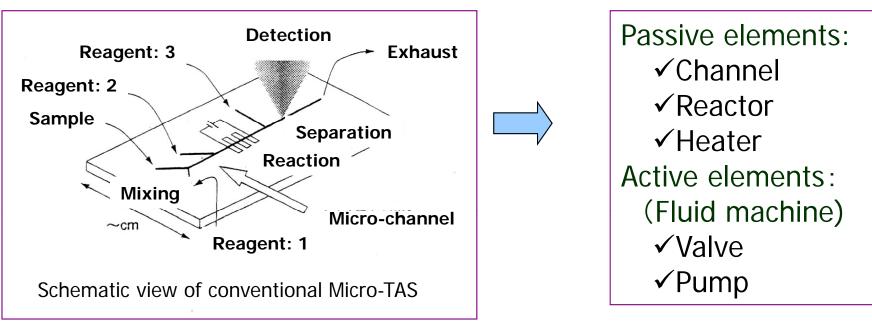
Miniaturization of biochemical analysis system

✓ Reduction of reagent and waste \rightarrow Reduction of environmental load ✓ Portability (in-situ monitoring) ✓ Medical doctor can give a diagnosis at clinic ✓ Clinic can monitor health condition of a patient \checkmark Patient can do routine self-examination at home ✓ Batch fabrication by MEMS technologies \checkmark Reduction of analysis time by parallel processing ✓ Low cost \checkmark Reduction of heat capacity \rightarrow Rapid reaction





Conventional Miniaturization of analysis system



Passive elements:channel, reaction-chamber →Possible of their miniaturization Active elements:pump, valve →Difficult to obtain sufficient output power



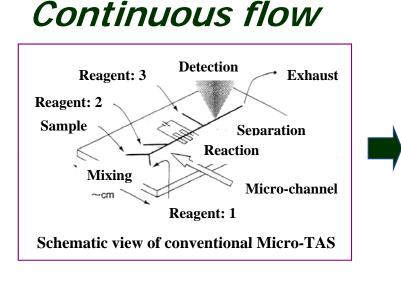
Difficult to miniaturize whole system by conventional MEMS technologies

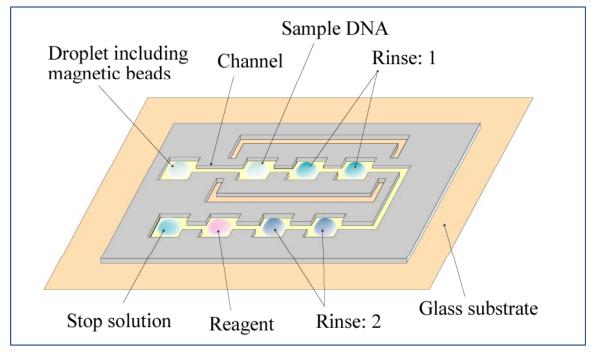




Droplet based reaction system

Droplet manipulation





 Building reaction systems by a series of chemical droplets
 Proposal of magnetic beads as a sample carrier

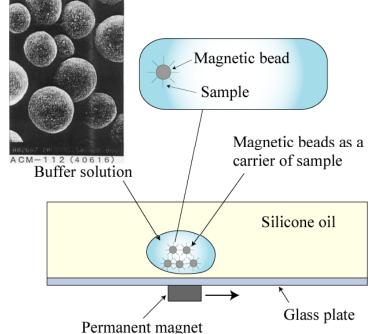




Magnetic beads handling

(1) Magnetic beads
Works as a sample carrier
(2) Magnetic driving force
→enable a handling of electrolyte solution

(3) Droplet formation by two solution
 Hydrophobic treatment of glass surface
 →enable a forming of lubricant film on glass surface



\rightarrow This system can manipulate magnetic beads without sticking onto glass surface

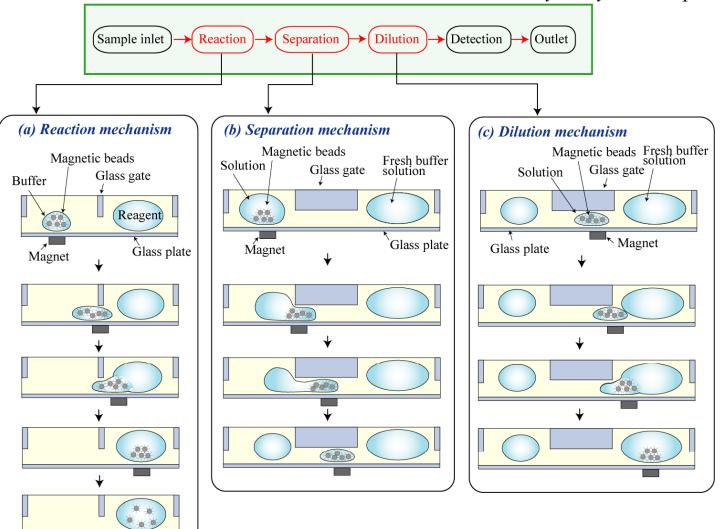
M. Shikida, et al., Sensors and Actuators A, 116, 2004, 264-271





System configuration example

Micro-Chemical Analysis System chip



M. Shikida, et al., Sensors and Actuators A, 116, 2004, 264-271





Advantages

- (1) Can miniaturize whole system, because it does not require active fluidic elements
- (2) Can transfer magnetic beads selectively between droplets
- (3) Can control dilution ratio by changing droplet volume (for example: x1000)





Beads: composite of magnetite and phenol-resin

- ✓ Ferromagnetic material : Magnetite
 - (diameter: 20nm)
- ✓ Resin : Phenol-resin (binder)

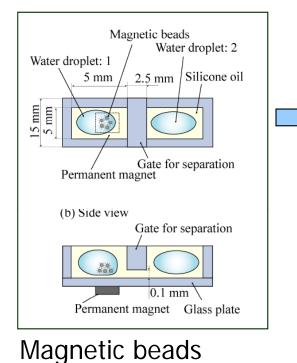
Magnetic properties

- ✓ Diameter d: 5.9-32.7 μ m
- \checkmark Density ρ : 3.62 g/cm^3
- ✓ Coercive force Hc: 3.6-5.9 kA/m
- \checkmark Residual magnetization $\sigma_r:$ 2.9-5.9 Am²/kg
- ✓ Saturated magnetization σ_s: 73.2 Am²/kg (0.33 Wb/m²)





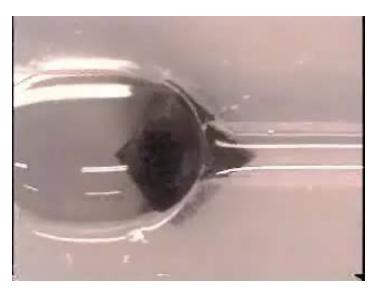
Magnetic beads operation

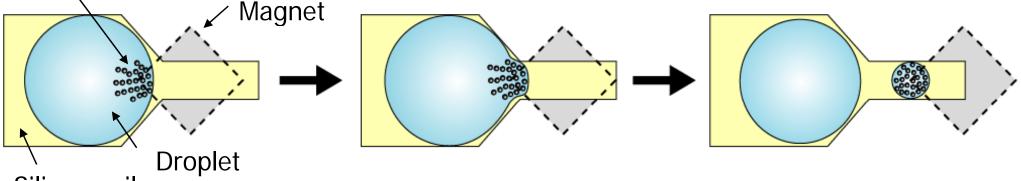


Planar type



Enable batch fabrication by resin mold



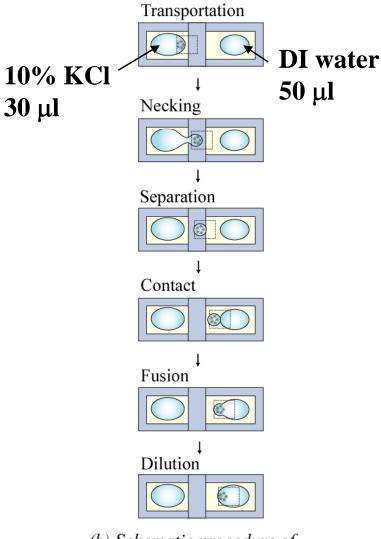


Silicone oil

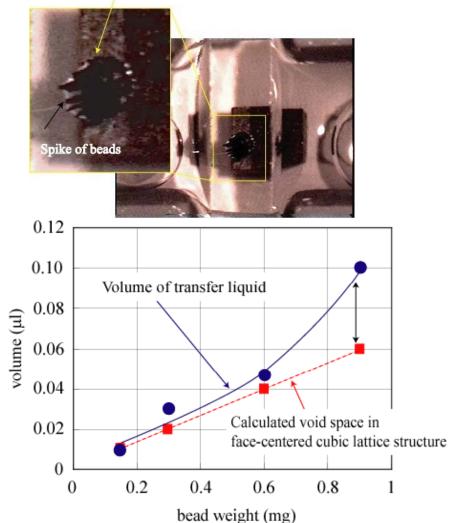




Associated fluid volume by beads extraction



(b) Schematic procedure of experiment(Beads separation and dilution) Bead cluster

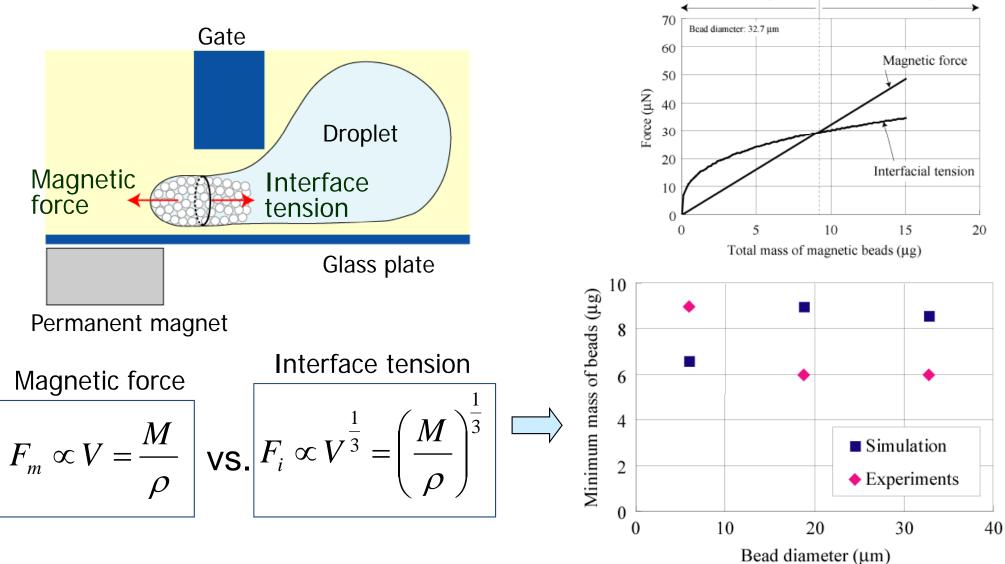


M. Shikida, et al., Sensors and Actuators A, 116, 2004, 264-271





Mechanical model for extraction



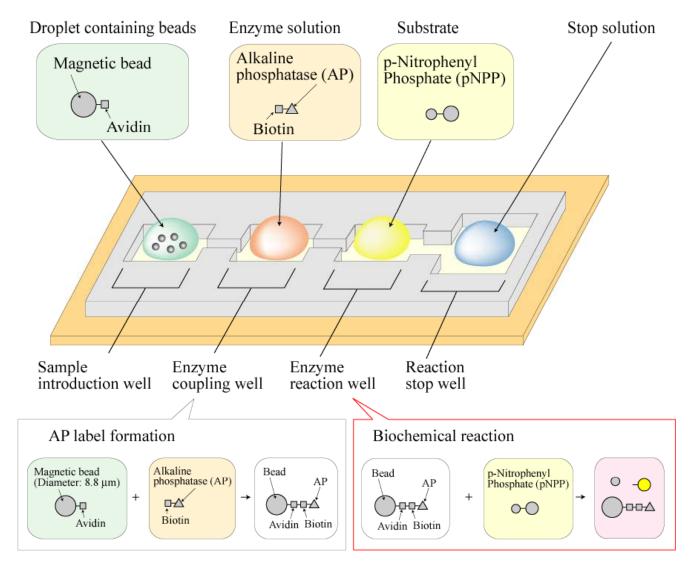
M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 1875-1883

Interfecial tension > Magnetic force. Interfecial tension < Magnetic force





Enzymatic reaction by magnetic beads

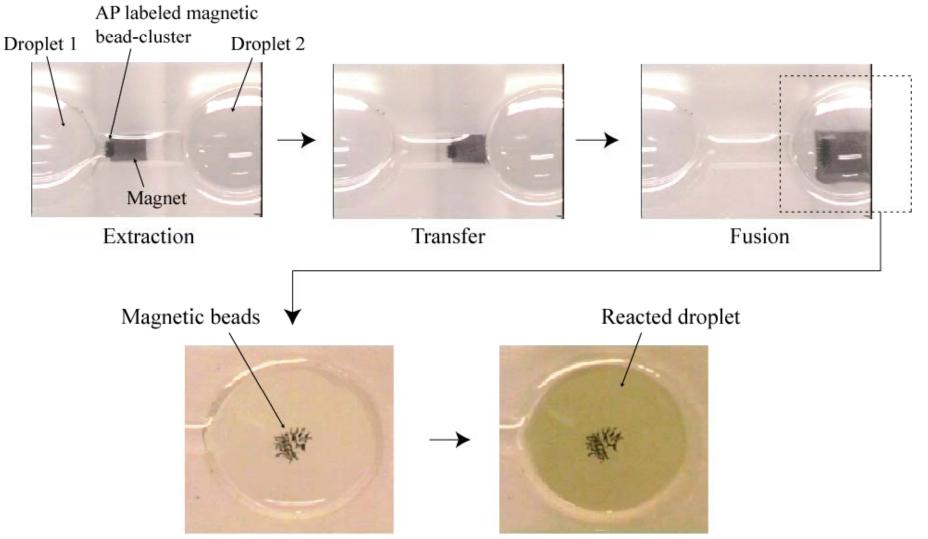


M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 1875-1883





Enzymatic reaction

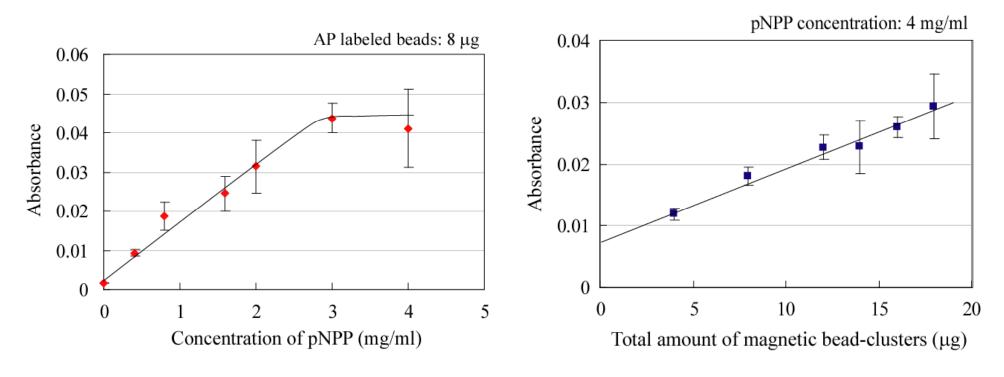


M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 1875-1883





Enzymatic reaction



Beads labeled by enzyme: 8 µg Reaction time: 20 min.

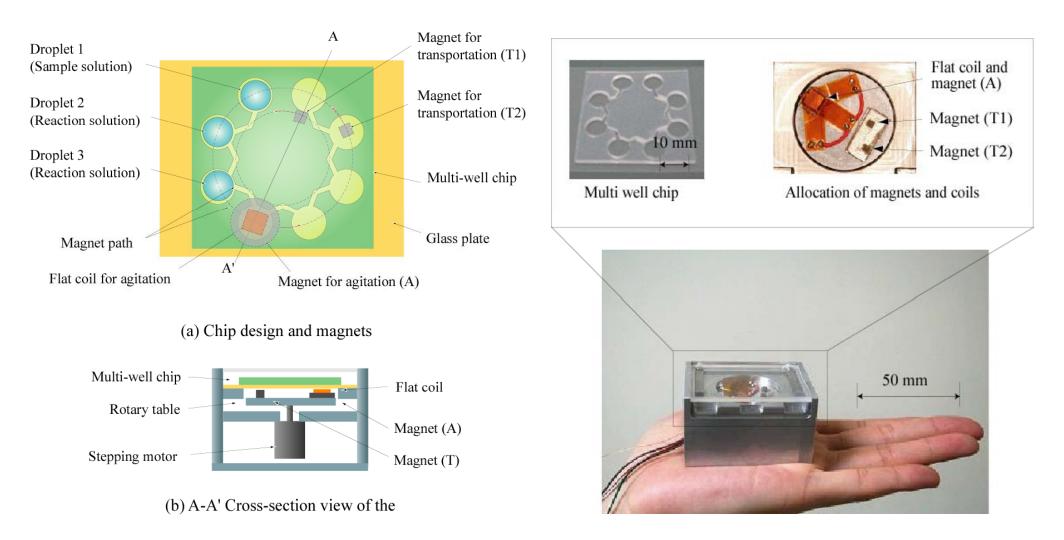
Substrate concentration : 4 μ g/ml Reaction time : 20 min.

M. Shikida, et al., J. Micromech. Microeng., 16, 2006, 1875-1883





Palm-top sized beads handling system



M. Shikida, et al., J. Micromech. Microeng., 18, 2008, 035034 (8pp)



